

# Spatial profile studies of



Nuclear material burn-up

# **Laser Ablation-Ionization**

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# **Burn-up measurements**



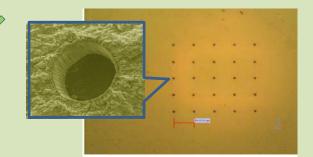


#### **Chemical Dissolution Method**

- Dissolution
- Chemical Separation
- Mass Spectrometer Analysis
- Traditional, ASTM Prescribed
- Spatial Profiling not possible
- ☐ Time consuming & Labour intensive
- Sample to be brought to laboratory

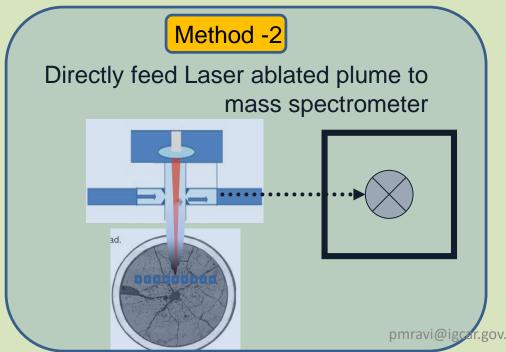
### **Proposed Laser Ablation**

- Avoids Dissolution
- Avoids Chemical Separation
- Mass Spectrometer Analysis
- New
- Spatial Profiling is possible
- Quick & Direct sampling
- Laser taken inside Hot Cells



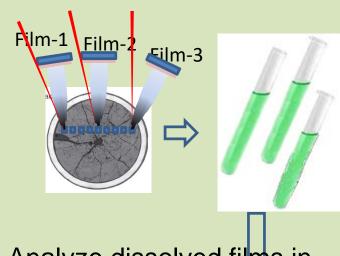
# Pulsed Laser - A Tool for analytical sampling



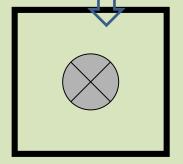


### Method -1

Deposit Thin films inside Hot Cell Dissolve films in nitric acid



Analyze dissolved films in mass spectrometer







### High Power Nanosecond Laser Pulse

- Laser Pulse strike material surface
- ☐ Thermal & non-thermal transfer of energy
- Following Physical Process Occurs
- (i) Evaporation (Laser heating)
- (ii) Electron & Ion ejection
- (iii) Particulates & atomic clusters ejection
- (iv) Plasma light emission

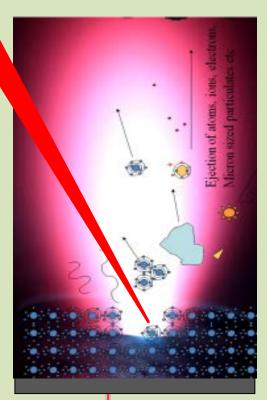


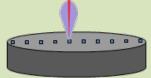




### **Physical Process of Laser Ablation**

- (i) Evaporation (Thermal Process Heating)
  - Neutral atom & molecules ejection.
  - Vapour composition governed by partial pressure of vaporizing species.
  - Temperature 3000 7000K (ns pulsed laser heating of refractory materials).
- (ii) Electron & Ion ejection
- (iii) Particulates & atomic clusters ejection
- (iv) Plasma light emission

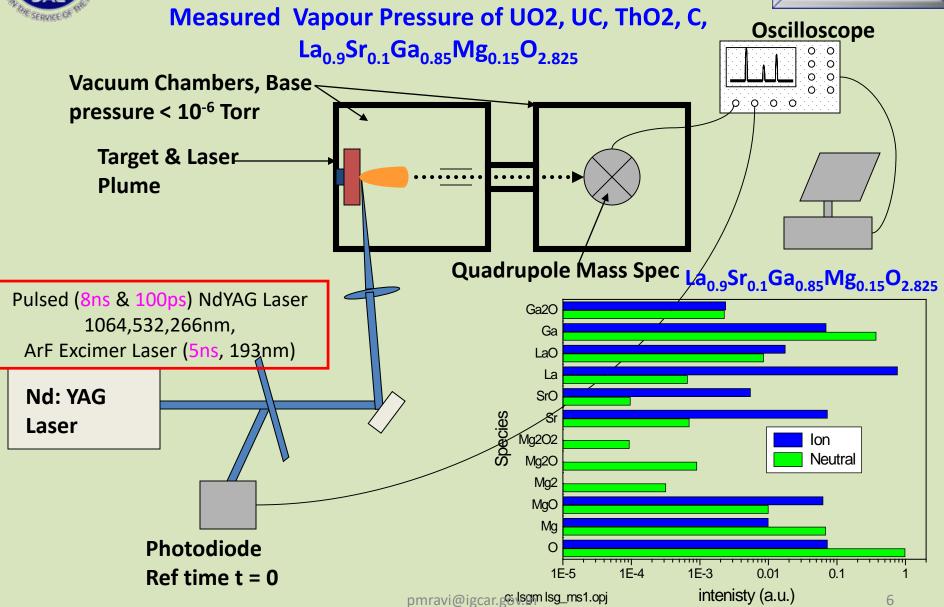






# Laser Vapourization -Mass Spectrometer (using QMS)



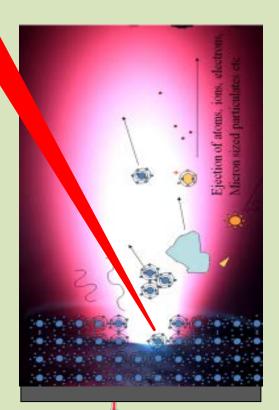






### **Physical Process of Laser Ablation**

- (i) Evaporation (Thermal Process Heating)
- (ii) Electron & Ion ejection
  - Laser produced lons are used.
  - Time of Flight Mass Spectrometer.
  - Spatial profiling / surface chemical & isotope mapping.
  - Quick Burn-up measurements.
- (iii) Particulates & atomic clusters ejection
- (iv) Plasma light emission



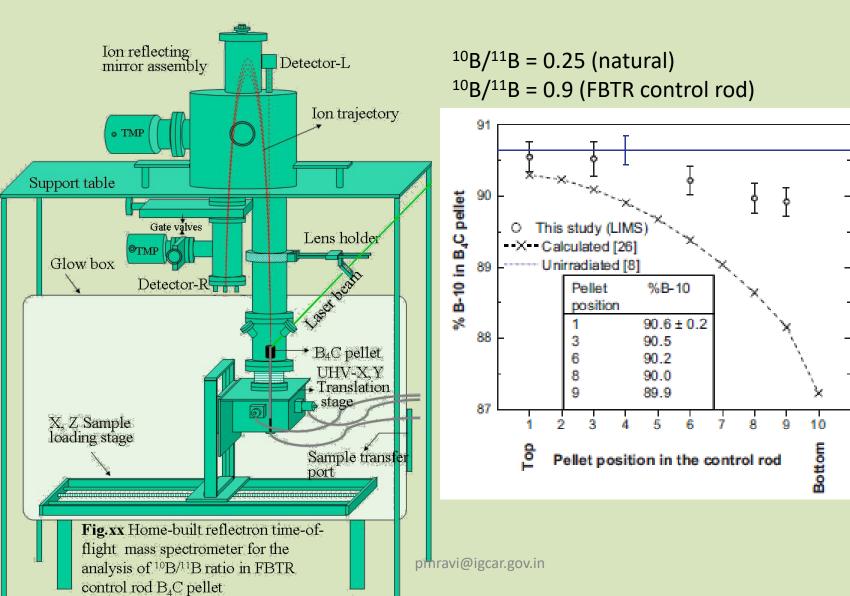




# Laser ablation - Time of flight Mass spectrometer



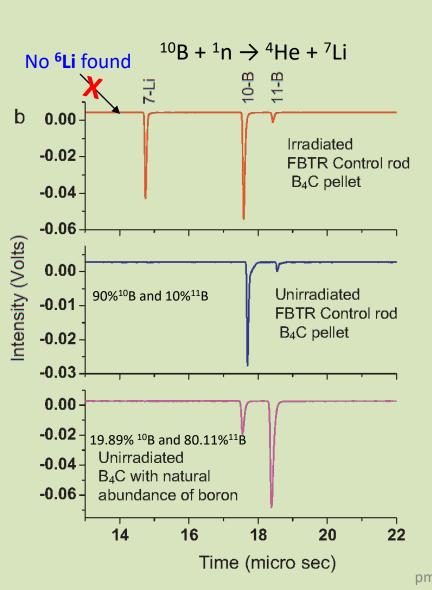
<sup>10</sup>B Isotope measurement in Irradiated B<sub>4</sub>C

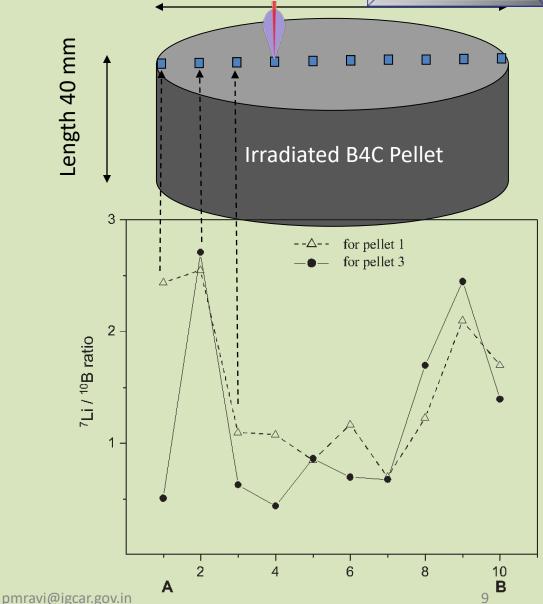




# Spatial Profile of $^{10}\text{B}$ Isotope consumption in Irradiated $B_4C$



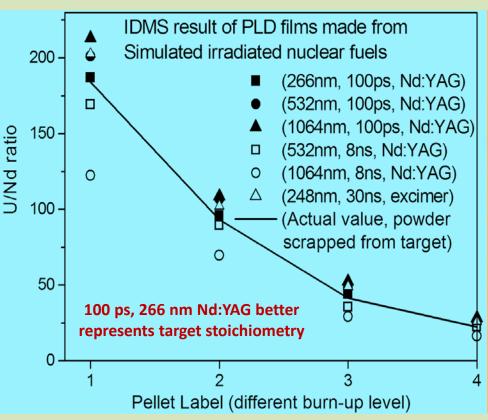


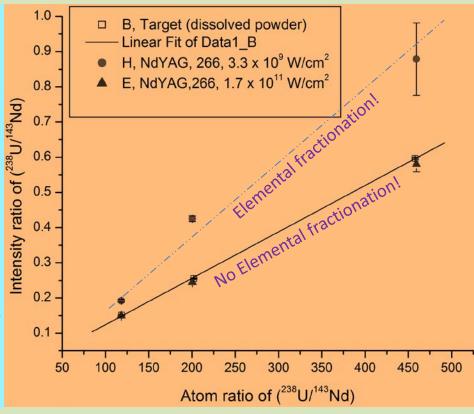


#### Laser-Mass Spectrometer (TOF) 0.00 -0.05 Number of atoms in 10 µl: Intensity(V) U= 1.06e19 Nd= 4.6e17 Nd-143=5.57e16 -0.15Nd-146=7.86e16 Sm=4.79e17 La=2.99e17 Ce=2.93e17 -0.20 -0.2590 100 110 120 130 Time(µs) (a) Intensity ratio (UO<sub>2</sub>\*/143NdO\*) 160 Linear Fit 0.00 148 [Sm+Nd]O 140 Intensity ratio of UO2\*/143NdO\* 120 -0.05 100 Intensity(V) Burn-up -0.10 measurement 20 -0.15 -800 1000 1200 104 102 103 100 101 Atoms ratio of (U/143Nd) in the sample solution Time(µs) (b) 10 pmravi@igcar.gov.in

# Which laser?

# At What Fluence?





Lower Wavelength & Lower Pulse duration are better!

Higher fluence is better!
However, Very high fluence is bad







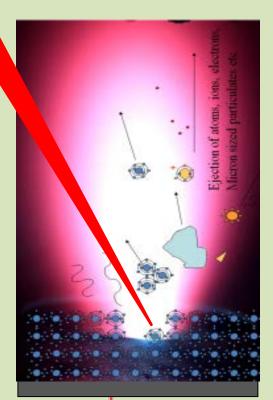


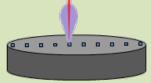
### **Physical Process of Laser Ablation**

- (i) Evaporation (Thermal Process Heating)
- (ii) Electron & Ion ejection

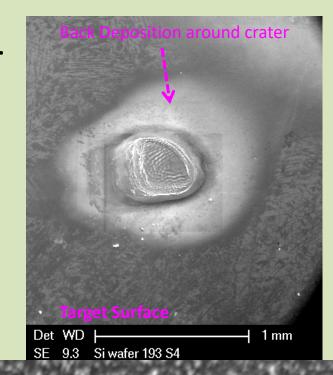
### (iii) Particulates & atomic clusters ejection

- Chip Off (broken from surface)
- Sub-surface boiling-condensation
- Sub micron size
- Ensures exact target chemical composition
- Perfect for ICP plasma digestion
- Sampling input for ICPMS -> LA-ICPMS
- Spatial Profiling / Chemical & isotope mapping
- (iv) Plasma light emission

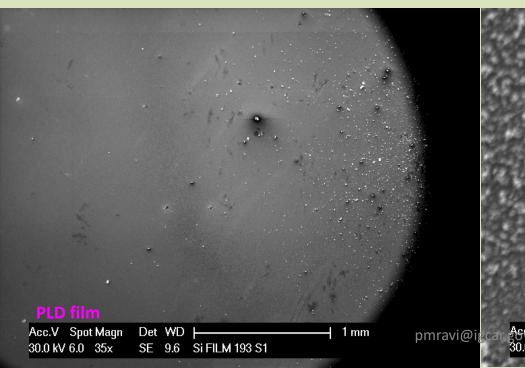


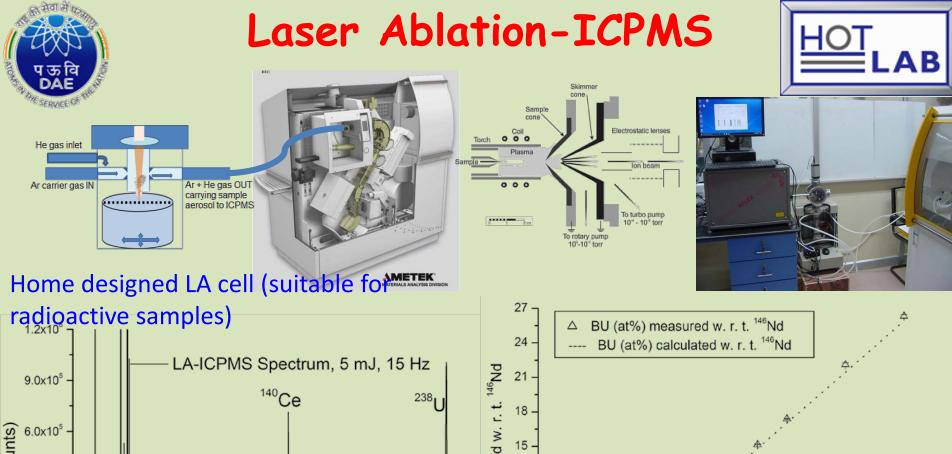


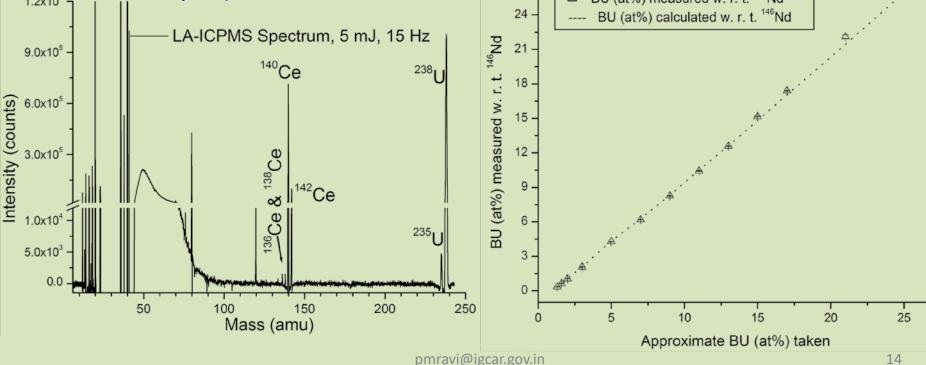
- Vapour Back Deposition (ambient pressure).
- Particulates: not back deposited.
- Particulates around 0.5 micron size good for ICP Plasma "digestion".
- Low laser fluence favours vapour.
- High laser fluence promotes particulates.



kV 6.0 1500x SE 9.5 Si FILM 193 S1











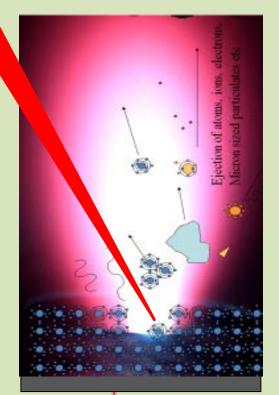
### **Physical Process of Laser Ablation**

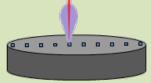
- (i) Evaporation (Thermal Process Heating)
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- (iii) Particulates & atomic clusters ejection

Mass Spectroscopy

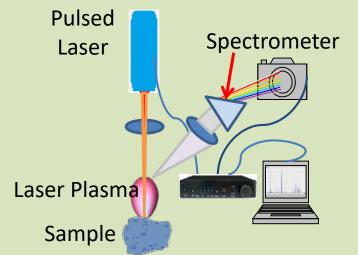
### (iv) Plasma light emission (Optical Spectroscopy)

- Laser Induced Breakdown Spectroscopy (LIBS).
- Laser plasma light captured by CCD Detector through Spectrometer, after "plasma cooling".
- Solid / Liquid / Gas samples
- Spatial Profiling / Surface Chemical mapping.
- Spatial isotope mapping?
- Fiber Optics allows "Easy" Glove Box / Hot Cell adptation.





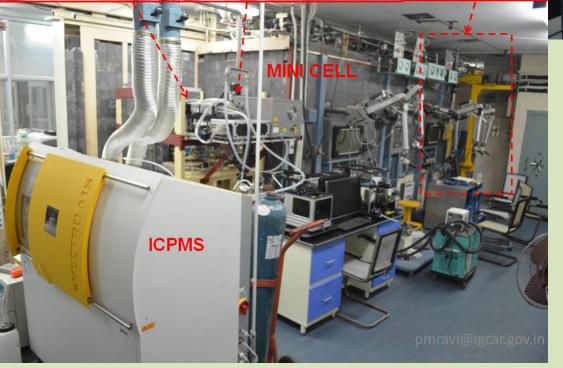
**LIBS for Active Sample Analysis** 



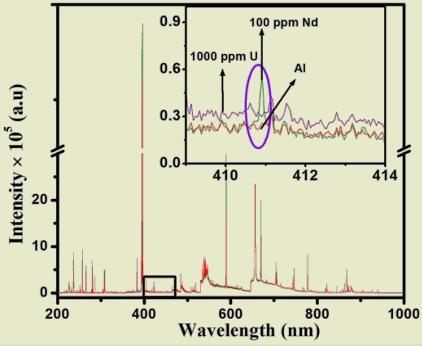
LIBS Sampling & Optics

Laser Ablation Sampling for ICPMS

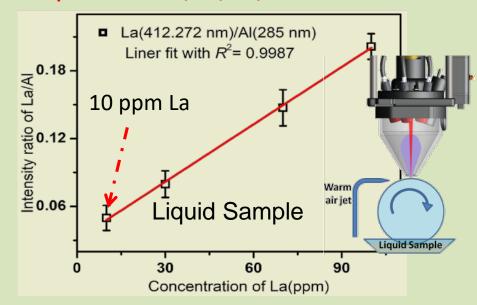
**ICP-AES** 



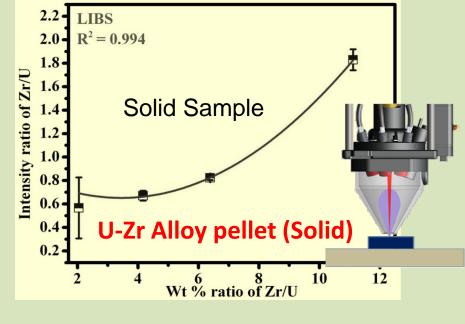
Mini Cell Facility (In Tandem with Hot Cell Facility) In Radio Chemistry Laboratory (IGCAR – Kalpakkam)

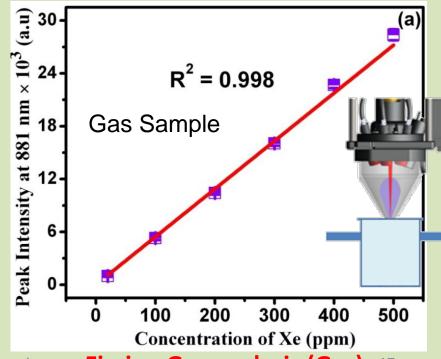


LIBS Spectrum of Nd, La, Sm, U in Nitric Acid



Fission products in HLLW (Liquid) pmravi@igcar.gov.in





Fission Gas analysis (Gas)

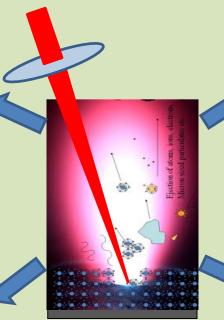
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# **Conclusions**



Quadrupole Mass Spectrometer **QMS** - Partial Pressure



Time of Flight Mass Spectrometer **TOF-MS** -Isotope & elemental ratio

ICP - MS

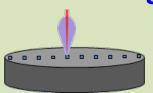
-Elemental Analysis

Laser Ablation Sampling

**LIBS** 

-Elemental Analysis

**Spatial Profiling in Solid Samples** 



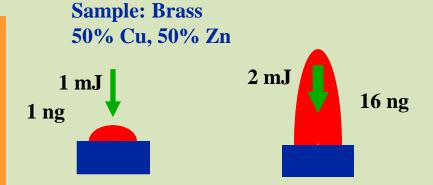


Solid, Liquid, Gas Samples

# Pulsed Laser Evaporation (Laser Ablation under thermal process)

- Quantity of ablated mass
  - Amount of ablated mass depend on laser energy non-linearly
    - » irradiance, wavelength, pulse width
- Composition (Chemistry) of ablated mass
  - Composition of ablated mass is different from the solid sample
  - Composition of ablated mass and sample can be the same under particular laser conditions

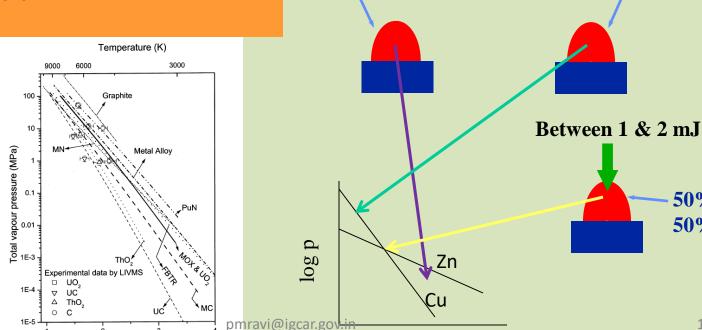
10⁴/T(K)



70% Cu, 30% Zn

50% Cu, 50% Zn

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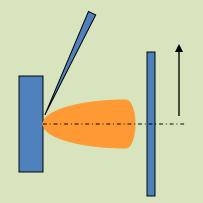
30% Cu, 70% Zn

1/T

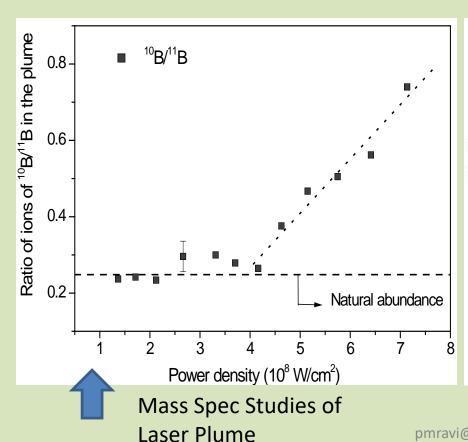


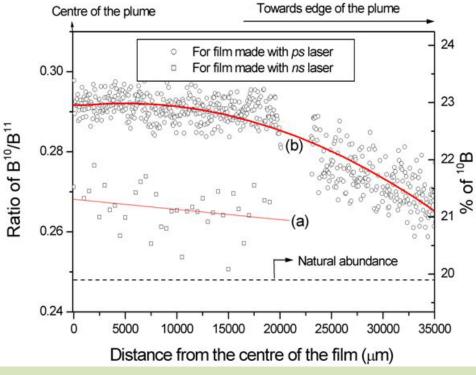
# Boron isotope ratio under high laser power density

Using higher laser power > 108 W/cm<sup>2</sup>



Distance from Centre of substrate





SIMS Studies of thin film